

Specification amendments.

Amend the paragraph starting at line 2 on page 1 of specification as follows:

Cross-Reference to Prior Applications

This application claims the benefit under 35 USC §119(e) of United States provisional application serial no. 60/192,766 filed March 28, 2000 and is a divisional of application serial no. 09/821,840 filed 9/23/2003.

Amend the paragraph starting at page 4, lines 29-30, by of specification as follows:

In the invention microfabrication techniques used for the fabrication of microelectro-mechanical systems (MEMS) coupled with sputter deposited thin film SMA actuation technology enable the mass production of device arrays with high current carrying microrelays. The SMA material can be made in thin film configurations in accordance with the teachings of U. S. patent 5,061,880 No. 5,061,914 to A. David Johnson et. al. Busch et. al. for Shape Memory Alloy Microactuator, the disclosure of which is incorporated by this reference.